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Chen et al.

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(54) **MULTIMODE INTERFERENCE COUPLER
FOR USE WITH SLOT PHOTONIC CRYSTAL
WAVEGUIDES**

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(73) Assignee: **Board of Regents, The University of Texas**, Austin, TX (US)

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(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 364 days.

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H01L 21/00 (2006.01)
G03F 1/00 (2006.01)

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385/132; 438/29; 438/31; 430/321

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385/15-16, 28, 31, 50, 129-132; 438/29,
438/31; 430/321

See application file for complete search history.

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Primary Examiner — Brian M. Healy

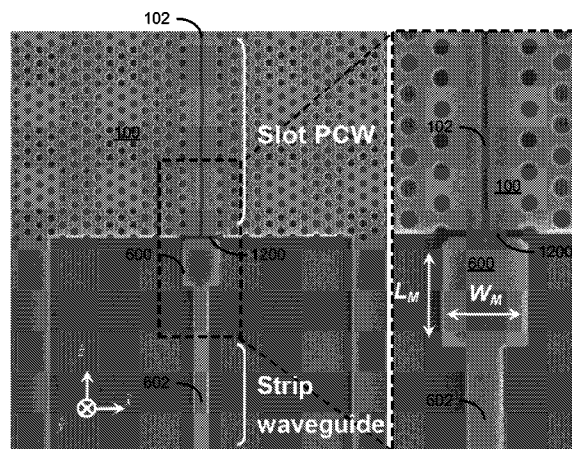
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(57) **ABSTRACT**

The present invention provides an optical apparatus having a multimode interference coupler configured to optically couple a strip waveguide to a slot photonic crystal waveguide. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero. The optical apparatus may also include an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

26 Claims, 10 Drawing Sheets



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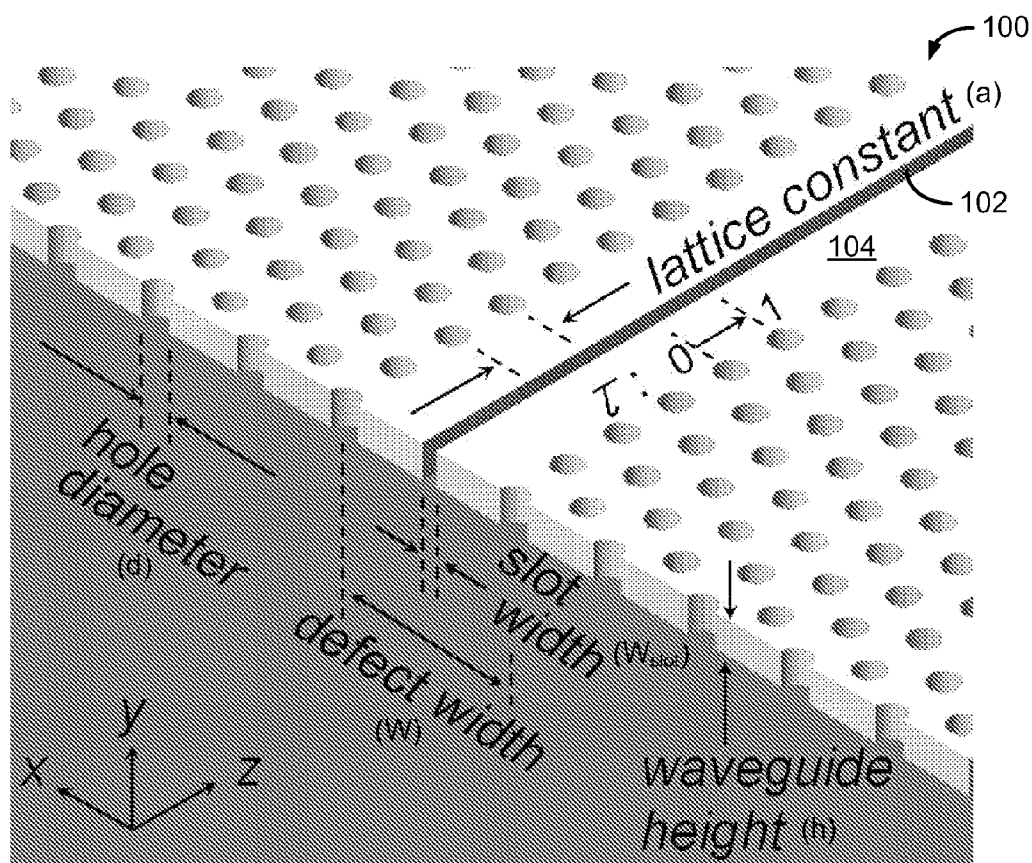


FIGURE 1

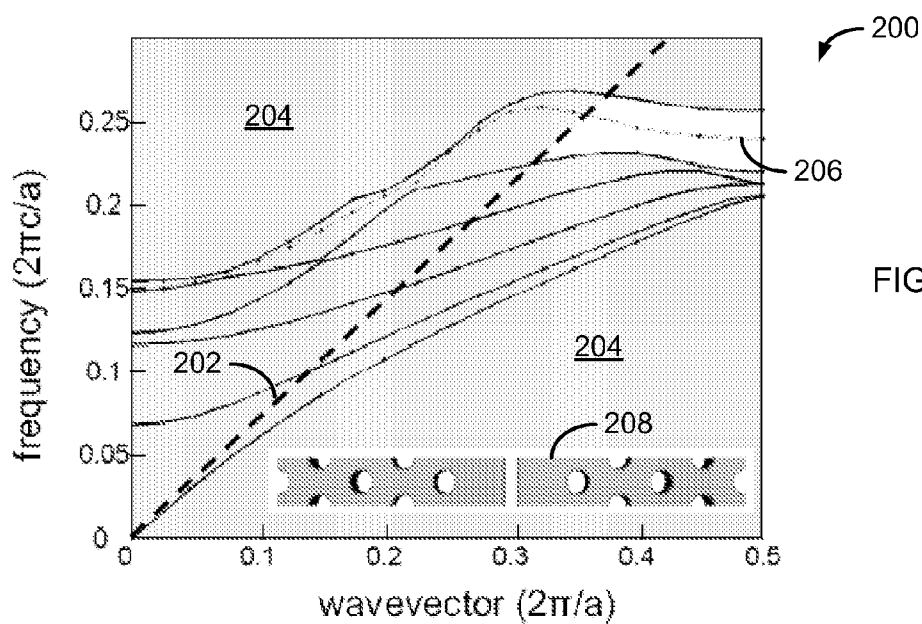


FIGURE 2

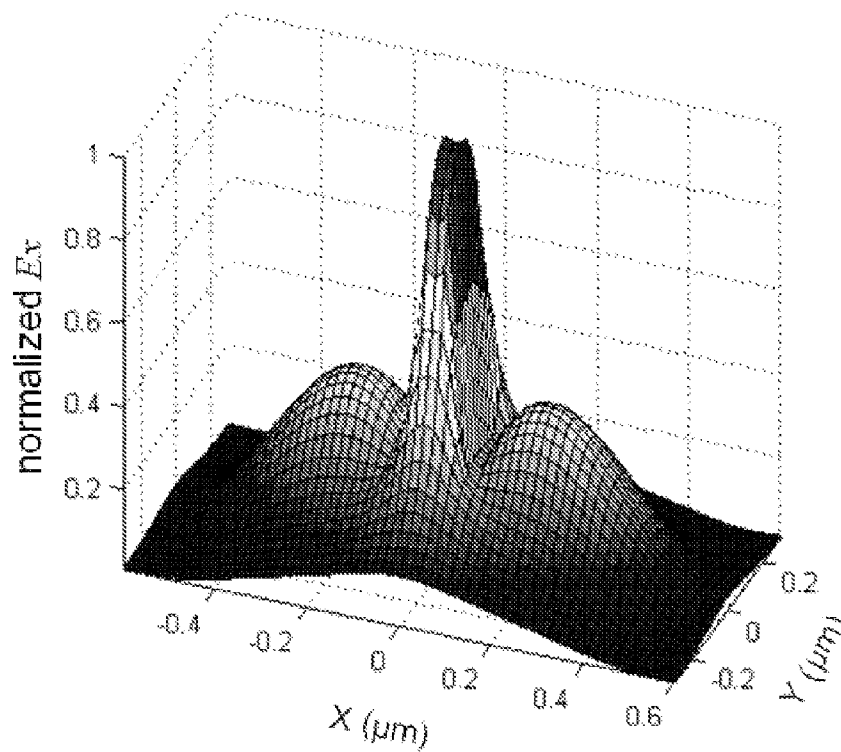


FIGURE 3

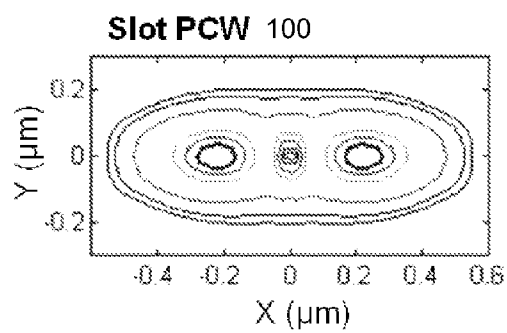


FIGURE 4

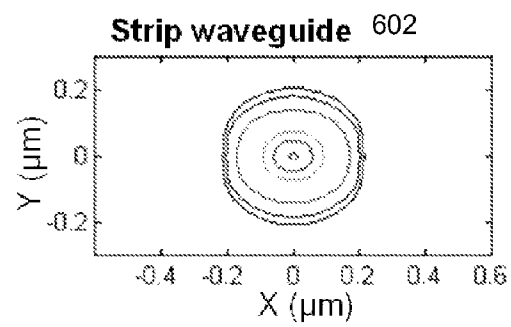


FIGURE 5

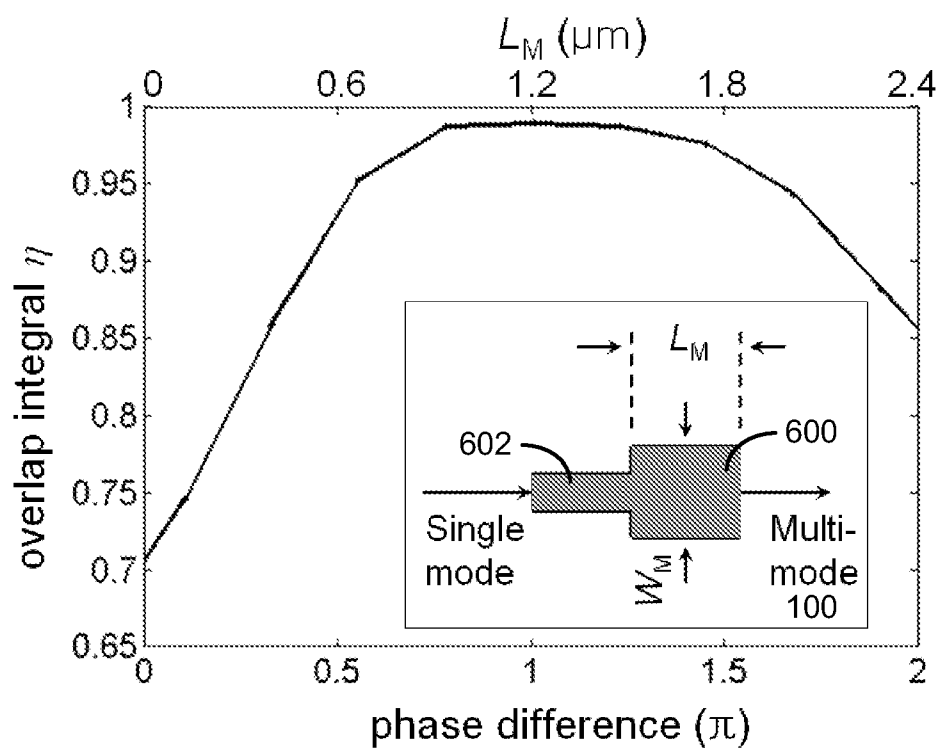


FIGURE 6

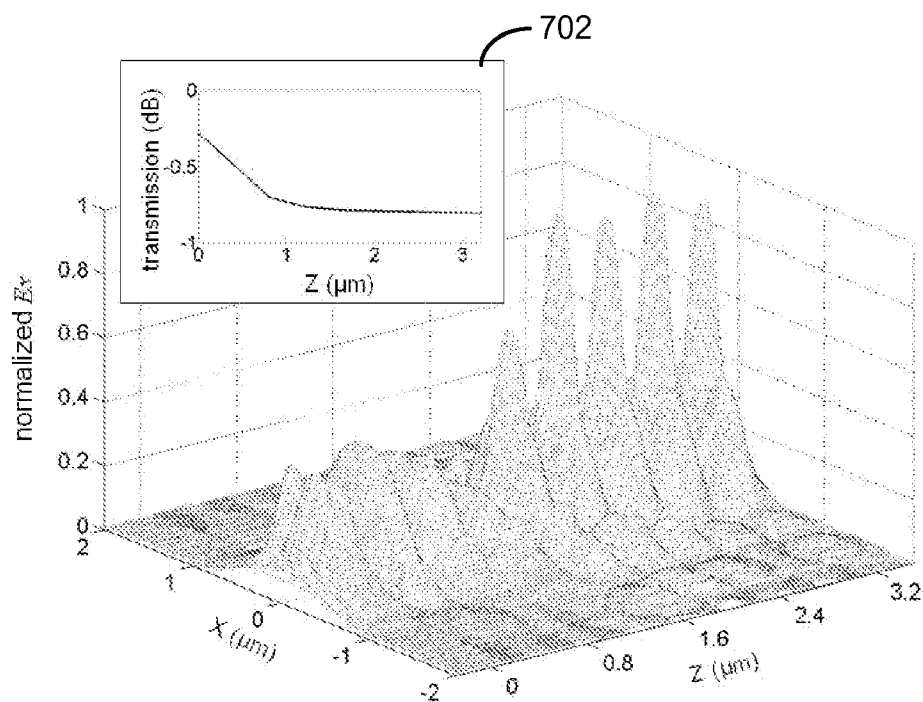


FIGURE 7

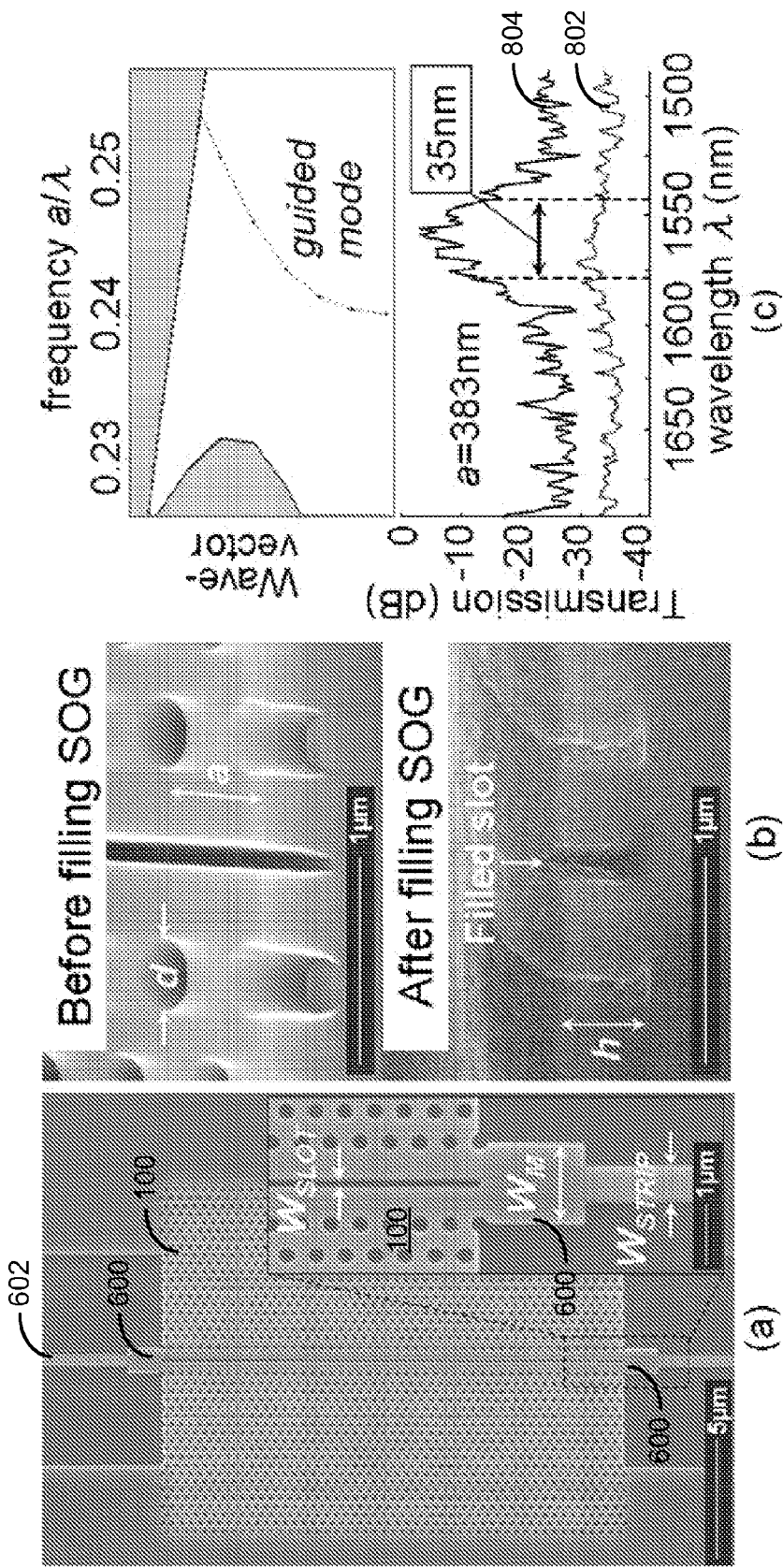


FIGURE 8

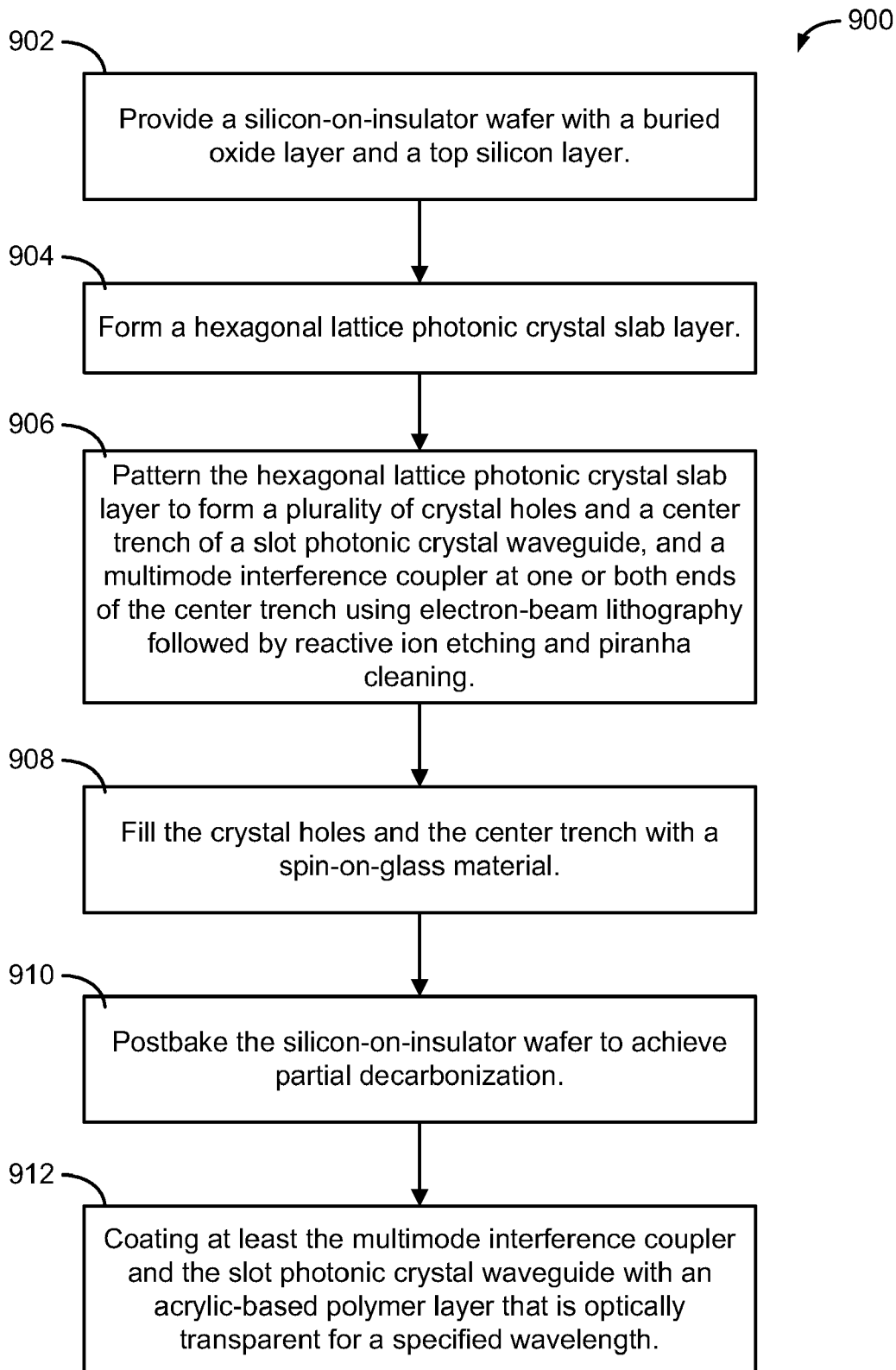


FIGURE 9

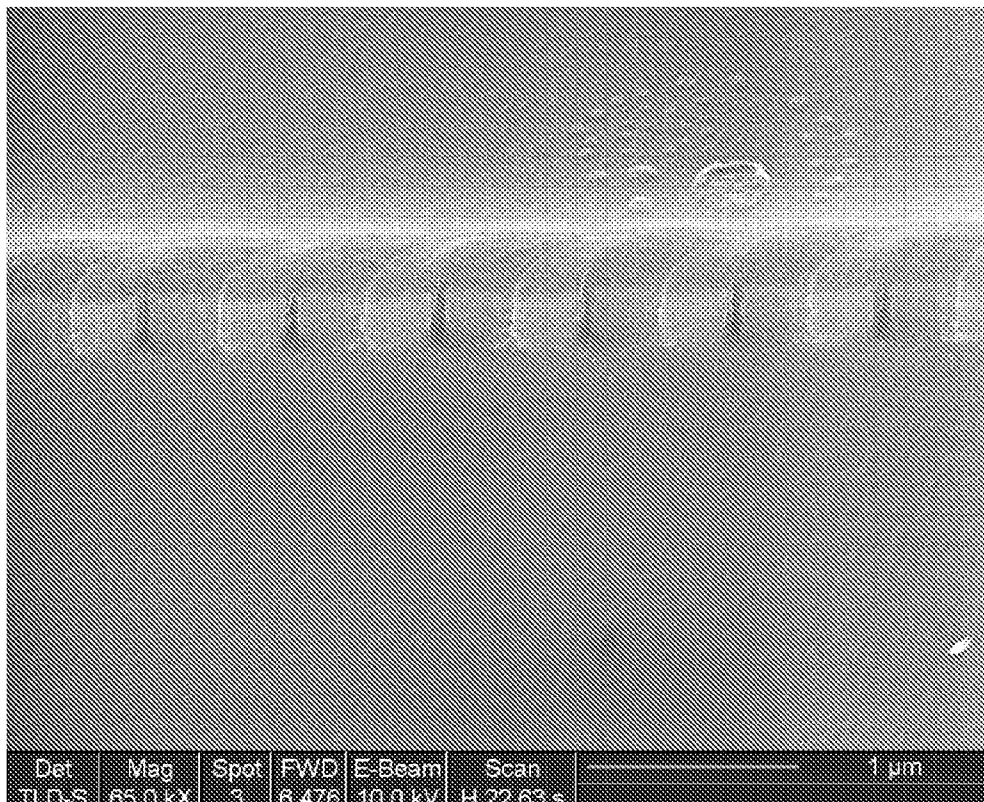


FIGURE 10

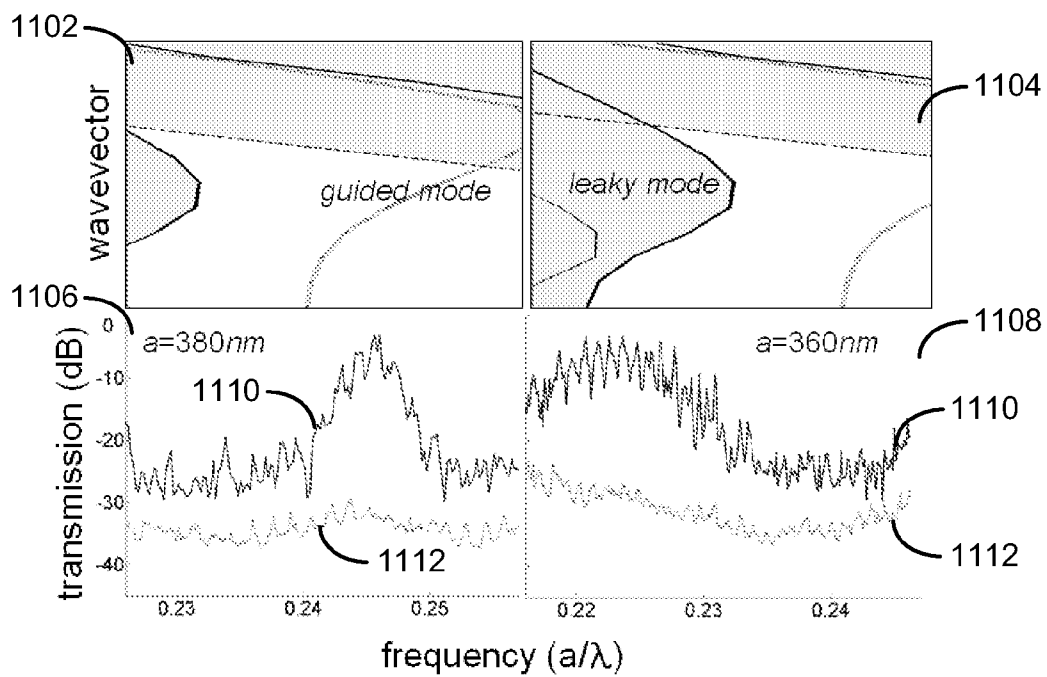


FIGURE 11

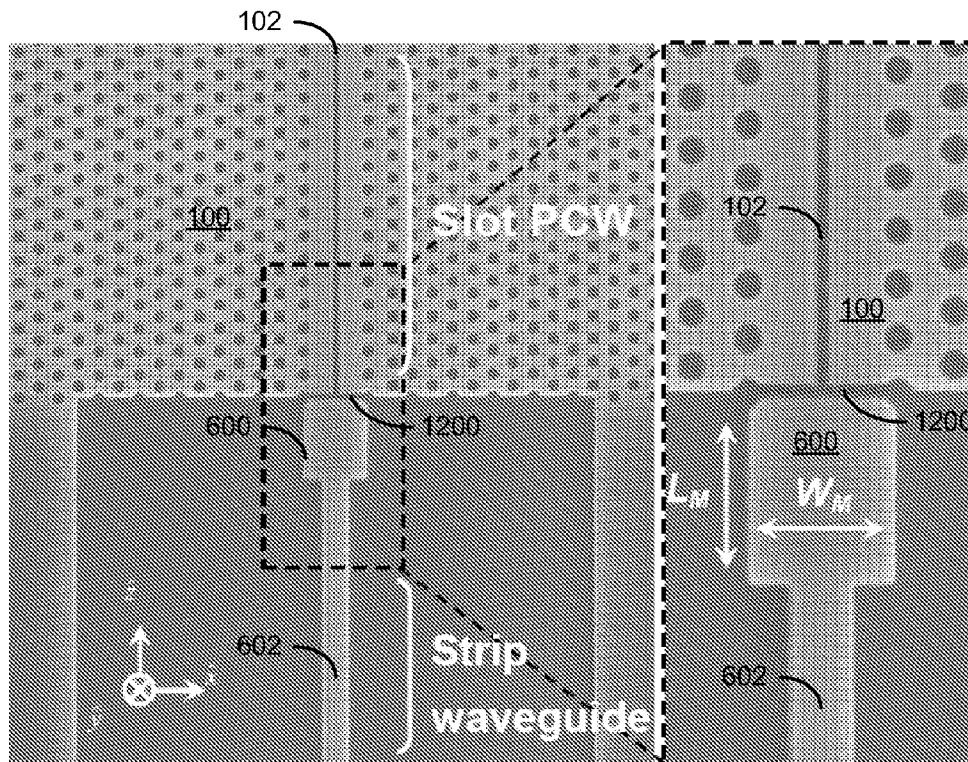


FIGURE 12

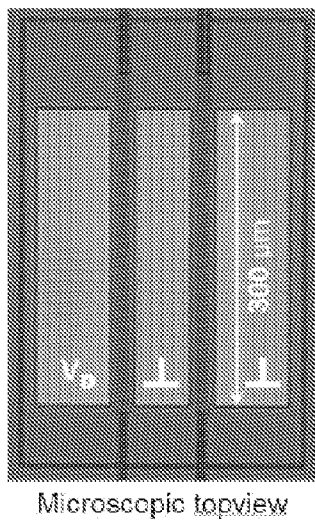


FIGURE 13

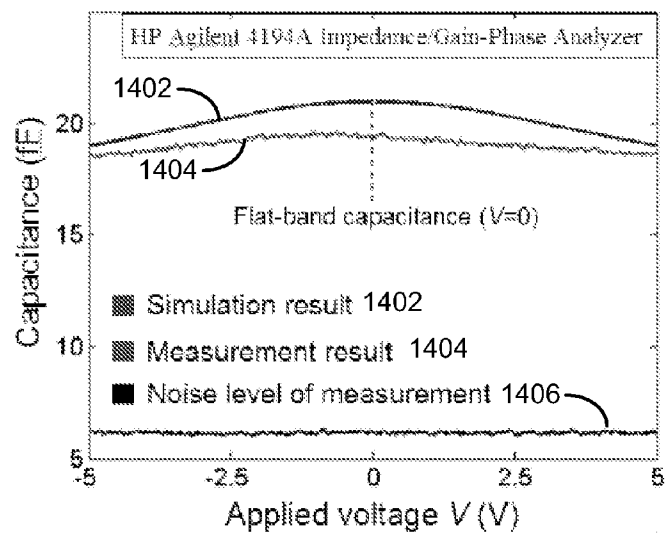


FIGURE 14

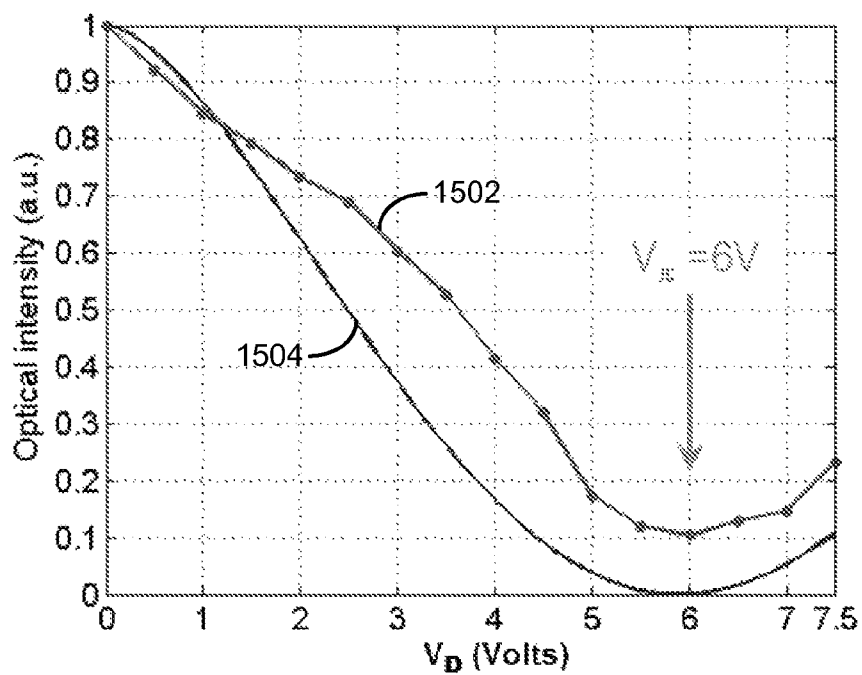


FIGURE 15

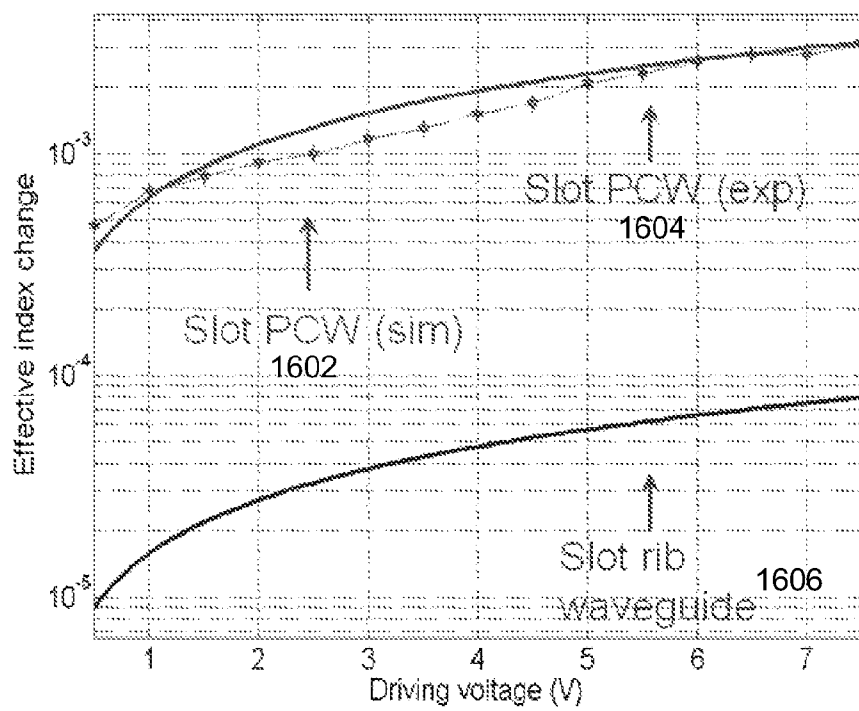


FIGURE 16

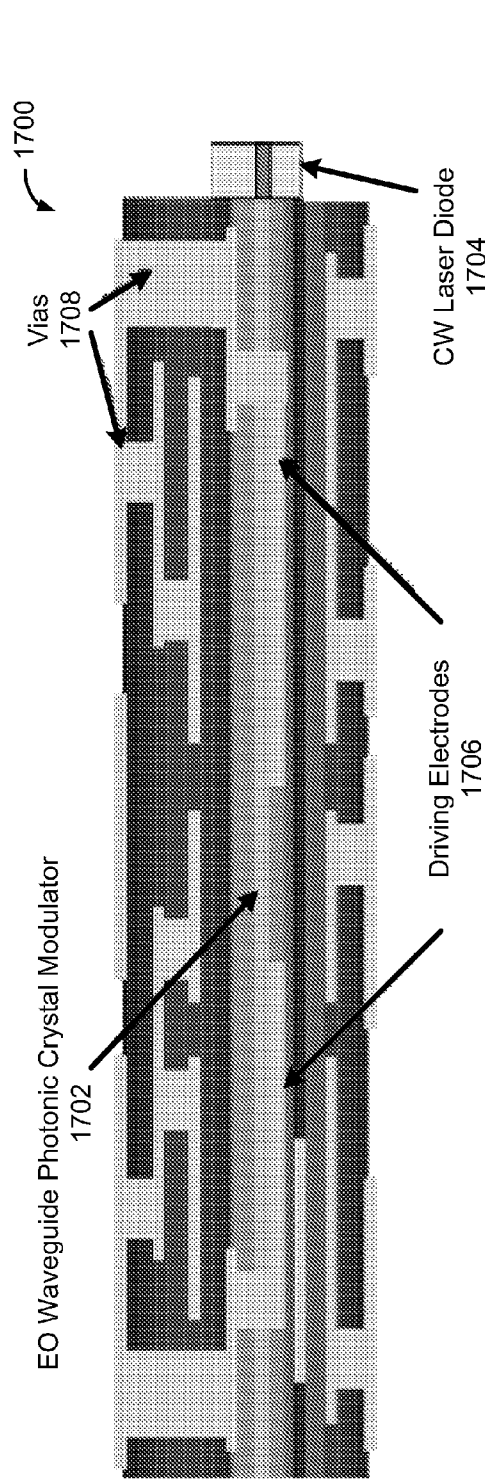


FIGURE 17

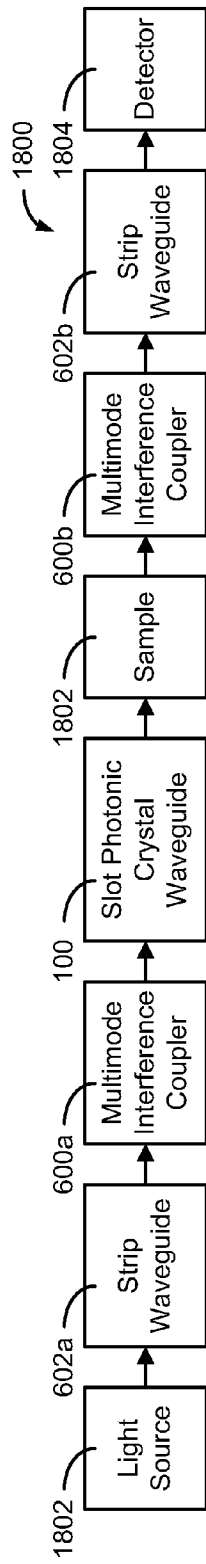


FIGURE 18A

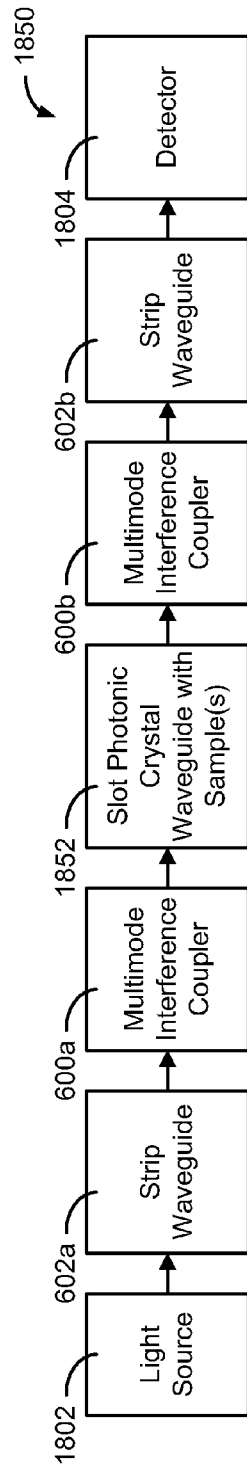


FIGURE 18B

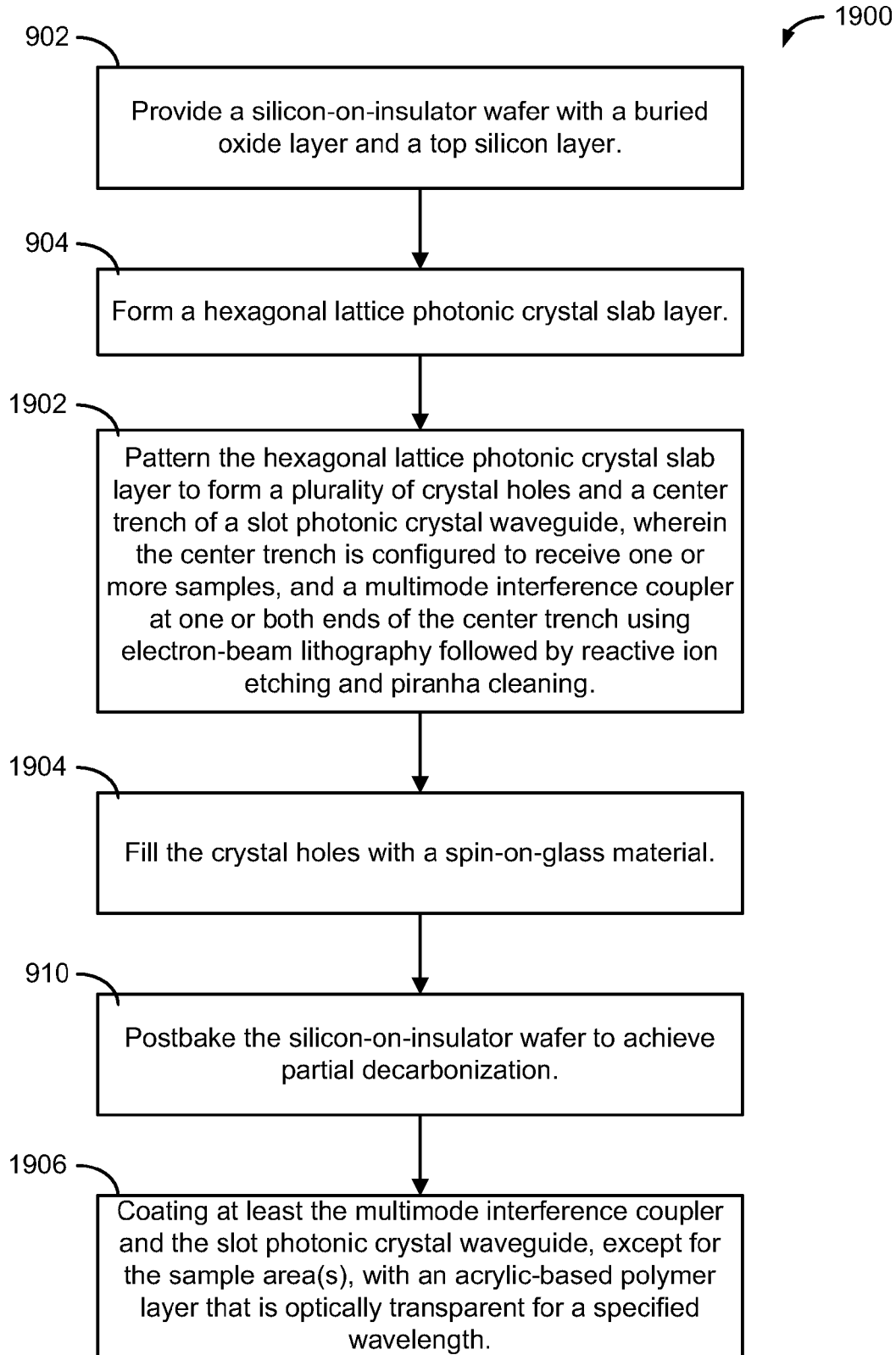


FIGURE 19

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MULTIMODE INTERFERENCE COUPLER FOR USE WITH SLOT PHOTONIC CRYSTAL WAVEGUIDES

CROSS-REFERENCE TO RELATED APPLICATIONS

This application claims benefit of U.S. provisional patent application Ser. No. 61/092,672 filed on Aug. 28, 2008 which is incorporated herein by reference in its entirety.

STATEMENT OF FEDERALLY FUNDED RESEARCH

This invention was made with U.S. Government support under contract number FA9550-05-C-0171 awarded by the Air Force Office of Scientific Research. The government has certain rights in this invention.

TECHNICAL FIELD OF THE INVENTION

The present invention relates in general to the field of optical waveguides, and more particularly to multimode interference couplers.

BACKGROUND OF THE INVENTION

Without limiting the scope of the invention, its background is described in connection with multimode interference couplers and photonic crystal waveguides. Introducing line defects into a photonic crystal lattice permits an electromagnetic wave having a frequency within the bandgap of the structure to be guided through the photonic crystal. The line defects resemble waveguides, and may be formed by either adding or removing dielectric material to a certain row or column along one of the directions of the photonic crystal lattice. Thus, photonic crystal waveguides can be used as an optical "wire" to guide an optical signal between different points, or devices, within an optical integrated circuit.

Photonic crystal waveguides (PCW) with low group velocity have been demonstrated recently to replace conventional optical switches and modulators [1-4], where the size of the active region is considerably reduced via slow light effect [5,6]. They typically consist of a periodic array of air holes on a dielectric substrate whose optical properties are modified by an external physical signal. One of the most efficient tuning methods may be based on the application of electro-optical material. It is well known that the unique properties of photonic crystals can be exploited to enhance the nonlinear effect drastically and thus a small attainable change in the refractive index can induce applicable optical response [7].

For example, U.S. Pat. No. 6,782,169 discloses a coupler having a dielectric mirror or Gaussian mirror to couple optical signals from a planar waveguide to a PCW. Although the mirrored coupler provides a coupling efficiency of greater than 80%, the coupler does not permit the optical path of the planar waveguide to be longitudinally aligned with the optical path of the PCW. In addition, the actual coupling efficiency of the coupler is dependant on the manufacturing quality of the mirror, which necessarily increases the cost and complexity of the coupler.

As disclosed in U.S. Pat. No. 5,889,906, multimode interference couplers of varying shapes have been used. The width of the wide end of these couplers is about 15 μm and the length of these couplers range between 200 μm and 600 μm . Another example of tapered couplers is disclosed in United States Patent Application Publication 2002/0159703. The width of

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the wide end of these couplers range between 10 μm and 50 μm , and the length of these couplers range between 150 μm to 500+ μm . These couplers require a taper length of more than several hundred of microns to reduce the propagation loss due to the requirement of adiabatic tapering.

The inventors previously disclosed that a simple MMI coupling structure between a channel waveguide and a PCW with a center trench can achieve a coupling efficiency of 70%. See X. Chen, L. GU, W. Jiang, R. Chen, "Active transmission control based on photonic-crystal MOS capacitor," *Proc. of SPIE*, vol. 6480, 64800W (2007), which is hereby incorporated by reference in its entirety. The MMI section interfaces with the slot PCW at the edge of the period that gives a termination parameter of $\tau=0.5$. The width of the coupler is equal to the defect width of the slot PCW and the length of the coupler is approximately 1.25 times the width of the coupler.

As a result, there is a need for a MMI coupling structure that is small, does not require complicated structures or fabrication, yet provides a coupling efficiency that exceeds 90%.

SUMMARY OF THE INVENTION

The present invention provides a novel multimode interference (MMI) coupler or structure integrated with a slot photonic crystal waveguide (PCW) for guiding light with low group velocity in a 100-nm-wide low-index region that provides unexpected results when: (a) the width (L_M) of the MMI coupler is adjusted to set the phase difference close to π ; and (b) the termination parameter (τ) is set to 0. The MMI coupler provides a 20 dB efficiency enhancement over a 35 nm optical bandwidth centered at the communication wavelength of 1550 nm compared with direct coupling configuration and has a coupling efficiency that exceeds 90%. In addition, the MMI coupler implements a more compact structure (e.g., 1.25 μm) compared to tapered MMI couplers (e.g., 10-500+ μm). As a result, the MMI coupler is a more efficient and practical device (cost, design, fabrication, reliability and power consumption) than prior art devices. These advantages are crucial for fully embedded board level interconnect where heat dissipation due to the fully embedded structure is a paramount concern. Moreover, the present invention can be used in sensors (e.g., bio-sensors, chemical sensors, structural sensors, etc.), telecommunications, fiber optics and data communications (e.g., routers, fully embedded board level interconnects, etc.) to name a few.

More specifically, one embodiment of the present invention provides an optical apparatus having a multimode interference coupler configured to optically couple a strip waveguide to a slot photonic crystal waveguide. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero. The length of the multimode interference coupler will often be equal to or less than 1.26 μm .

Another embodiment of the present invention provides an optical apparatus having a multimode interference coupler configured to optically couple a strip waveguide to a slot photonic crystal waveguide. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to $1.6\sqrt{3}\alpha$ where α is a lattice constant of the slot photonic crystal waveguide, a length that is approximately equal to $\pi/(\beta_0-\beta_2)$ where β_0 is a fundamental

mode propagation constant in the multimode interference coupler and β_2 is a second order propagation constant in the multimode interference coupler, and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.

Yet another embodiment of the present invention provides an optical apparatus having a strip waveguide, a slot photonic crystal waveguide and a multimode interference coupler disposed between the strip waveguide and the slot photonic crystal waveguide. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero. The length of the multimode interference coupler will often be equal to or less than 1.26 μm .

The present invention also provides a method for improving performance of an optical communication system by designing a multimode interference coupler having a width that is approximately equal to $1.6\sqrt{3}\alpha$ where α is a lattice constant of a slot photonic crystal waveguide, a length that is approximately equal to $\pi/(\beta_0 - \beta_2)$ where β_0 is a fundamental mode propagation constant in the multimode interference coupler and β_2 is a second order propagation constant in the multimode interference coupler. The multimode interference coupler is then fabricated between a strip waveguide and the slot photonic crystal waveguide such that the multimode interference coupler interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.

In addition, the foregoing optical devices may include an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap. The resulting multimode interference coupler provides an efficiency enhancement of approximately thirty times that of a slotted silicon rib waveguide.

Moreover, the present invention provides a method for manufacturing an optical apparatus by providing a silicon-on-insulator wafer with a buried oxide layer and a top silicon layer and forming a hexagonal lattice photonic crystal slab layer. The hexagonal lattice photonic crystal slab layer is then patterned to form a plurality of crystal holes and a center trench of a slot photonic crystal waveguide, and a multimode interference coupler at one or both ends of the center trench using electron-beam lithography followed by reactive ion etching and piranha cleaning. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero. The crystal holes and the center trench are filled with a spin-on-glass material and the silicon-on-insulator wafer is postbaked to achieve partial decarbonization. At least the multimode interference coupler and the slot photonic crystal waveguide are then coated with an acrylic-based polymer layer that is optically transparent for a specified wavelength.

Note that the step of patterning the hexagonal lattice photonic crystal slab layer can further form an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the

multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

Furthermore, the present invention provides a method for manufacturing an optical apparatus by providing a silicon-on-insulator wafer with a buried oxide layer and a top silicon layer and forming a hexagonal lattice photonic crystal slab layer. The hexagonal lattice photonic crystal slab layer is then patterned to form a plurality of crystal holes and a center trench of a slot photonic crystal waveguide, wherein at least a portion of the center trench is configured to receive one or more samples, and a multimode interference coupler at one or both ends of the center trench using electron-beam lithography followed by reactive ion etching and piranha cleaning. The multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero. The crystal holes are filled with a spin-on-glass material and the silicon-on-insulator wafer is postbaked to achieve partial decarbonization. At least the multimode interference coupler and the slot photonic crystal waveguide, except for the portion of the center trench that is configured to receive the one or more samples, are then coated with an acrylic-based polymer layer that is optically transparent for a specified wavelength.

The present invention is described in detail below with reference to the accompanying drawings.

BRIEF DESCRIPTION OF THE DRAWINGS

For a more complete understanding of the features and advantages of the present invention, reference is now made to the detailed description of the invention along with the accompanying figures and in which:

FIG. 1 is a diagram of a slot PCW in accordance with one embodiment of the present invention;

FIG. 2 is a band diagram for a slot PCW shown in FIG. 1;

FIG. 3 is a 3D graphical profile of the transverse electric field amplitude of the quasi-TE mode in a slot photonic crystal waveguide in accordance with one embodiment of the present invention;

FIG. 4 is a diagram of two dimensional field amplitude contours of a slot PCW in accordance with one embodiment of the present invention;

FIG. 5 is a diagram of two dimensional field amplitude contours of a single mode strip waveguide in accordance with one embodiment of the present invention;

FIG. 6 is a graph showing the optimization of the mode overlap integral between the slot PCW and the multimode section as a function of phase difference and length, and the dimensions of the MMI coupler (inset) in accordance with one embodiment of the present invention;

FIG. 7 is a picture of FDTD simulation results and an inset showing the transmission of the guided quasi-TE mode as a function of the propagation distance in accordance with one embodiment of the present invention;

FIG. 8(a) is a scanning electron microscopy picture with a top view of a slot PCW 100 integrated with two MMI couplers 600 with an insert enlarging the coupling region in accordance with one embodiment of the present invention;

FIG. 8(b) is a picture of a cross-sectional view of the slot PCW 100 before (top) and after (bottom) filling SOG in accordance with one embodiment of the present invention;

FIG. 8(c) is an enlarged portion of the dispersion diagram for the guided mode (top graph) and a transmission spectra of

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a 320 μm slot PCW with (solid) and without (dashed) the MMI coupler (bottom graph) in accordance with one embodiment of the present invention;

FIG. 9 is a flow chart of a manufacturing process to fabricate an optical apparatus in accordance with one embodiment of the present invention;

FIG. 10 is a picture of a cross-sectional view of the slot PCW **100** showing that all the void nanostructures in the waveguide slab layer have been filled with SOG in accordance with one embodiment of the present invention;

FIG. 11 are graphs showing the experimental results of the optical spectra for both guided mode and leaky modes in accordance with one embodiment of the present invention;

FIG. 12 is a diagram of a MMI coupler between a slot PCW and a strip waveguide in accordance with another embodiment of the present invention;

FIG. 13 is a microscopic top view of the symmetric Mach-Zehnder interferometer containing two SOS-capacitor-based phase shifters in accordance with another embodiment of the present invention;

FIG. 14 is a graph showing the simulation and measurement results of device capacitance as a function of the applied voltage in accordance with another embodiment of the present invention;

FIG. 15 is a graph of a DC modulation curve in accordance with another embodiment of the present invention;

FIG. 16 is a graph of the effective index change induced by different driving voltage in accordance with another embodiment of the present invention;

FIG. 17 is a cross-section of a fully embedded board level optical interconnect with an indirect modulation employing a photonic crystal waveguide modulator in accordance with another embodiment of the present invention;

FIGS. 18A and 18B are block diagrams of sensors in accordance with the present invention; and

FIG. 19 is a flow chart of a manufacturing process to fabricate a slot PCW having one or more sample recesses within the center slot optically coupled to a MMI coupler that is used as part of a sensor in accordance with the present invention.

DETAILED DESCRIPTION OF THE INVENTION

While the making and using of various embodiments of the present invention are discussed in detail below, it should be appreciated that the present invention provides many applicable inventive concepts that can be embodied in a wide variety of specific contexts. The specific embodiments discussed herein are merely illustrative of specific ways to make and use the invention and do not delimit the scope of the invention.

To facilitate the understanding of this invention, a number of terms are defined below. Terms defined herein have meanings as commonly understood by a person of ordinary skill in the areas relevant to the present invention. Terms such as “a”, “an” and “the” are not intended to refer to only a singular entity, but include the general class of which a specific example may be used for illustration. The terminology herein is used to describe specific embodiments of the invention, but their usage does not delimit the invention, except as outlined in the claims.

The present invention provides a novel multimode interference (MMI) coupler or structure integrated with a slot photonic crystal waveguide (PCW) for guiding light with low group velocity in a 100-nm-wide low-index region that provides unexpected results when: (a) the width (L_M) of the MMI coupler is adjusted to set the phase difference close to π ; and

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(b) the termination parameter (τ) is set to 0. The MMI coupler provides a 20 dB efficiency enhancement over a 35 nm optical bandwidth centered at the communication wavelength of 1550 nm compared with direct coupling configuration and has a coupling efficiency that exceeds 90%. In addition, the MMI coupler implements a more compact structure (e.g., 1.25 μm) compared to tapered MMI couplers (e.g., 10-500+ μm). As a result, the MMI coupler is a more efficient and practical device (cost, design, fabrication, reliability and power consumption) than prior art devices. These advantages are crucial for fully embedded board level interconnect where heat dissipation due to the fully embedded structure is a paramount concern. Moreover, the present invention can be used in sensors (e.g., bio-sensors, chemical sensors, structural sensors, etc.), telecommunications, fiber optics and data communications (e.g., routers, fully embedded board level interconnects, etc.) to name a few.

The slot PCW exhibits low group velocity near the band edge and therefore leads to a significant enhancement of nonlinear effect for active devices. The waveguide structure produces high electric field amplitude in a narrow low-index region and provides a feasible approach to apply low-index active materials in highly integrated optical circuits. With proper doping of the left and right silicon regions, a high external field can be generated across the narrow slot with a low voltage. This maximizes the overlap of a high optical mode field and a high external electric field and, together with the low group velocity, provides a promising approach to applying low-index EO materials in highly integrated optical circuits. In addition, the measured transmission spectra are in good agreement with simulated band diagram.

In order to apply the improved electro-optical effects in waveguide devices and to satisfy the low power requirement, a guided mode needs to be excited within a narrow active material region. An integrated optical waveguide called a slot waveguide opens the opportunity for guiding and confining light in a 100-nm-wide slot filled with low-refractive-index electro-optical materials [8, 9]. These nanostructures are embedded in photonic crystals and a slot PCW configuration is designed in order to combine the unusual optical features of photonic crystals and slot waveguides. A compact MMI structure or coupler is integrated and optimized to maximize the coupling efficiency from strip waveguides to the slotted region.

The design of the slot PCW **100** will now be described in reference to FIG. 1. The slot PCW **100** is a line defect structure with a low-index nanometer-size center slot **102** embedded in a photonic crystal slab **104**. The slotted photonic crystal slab **104**, with high refractive index $n_{Si}=3.48$, is sandwiched between two low-index regions with $n_{SiO_2}=1.46$. Theoretical analysis predicts that such photonic crystal structures with high index contrast in the vertical direction support an in-plane photonic band gap that lies below the light line [11, 12]. Defect modes within the gap region can be created by various line defects [13]. The line defect is generated in the photonic crystal slab **104** by replacing a single row of holes with a narrow slot **102** and enlarging the width of the defect region to create a relatively large effective core area of the waveguide **100**. The scattering loss due to side-wall roughness can therefore be reduced with larger waveguide width [14]. As a wider defect region may induce multiple bands into the gap region, care must be taken to design the enlarged defect width [15].

The slot PCW **100** is defined by the following variables:

- Defect width (W);
- Hole diameter (d);
- Lattice constant (α);

Slot width (W_{slot});
 termination parameter (τ) where $0 \leq \tau \leq 1$; and
 Waveguide height (h).

A three-dimensional (3D) fully vectorial plane-wave expansion (PWE) method is used to calculate the dispersion diagram of the slot PCW **100**. In this case, the hole diameter (d) is 0.5α and the waveguide height (h) is 0.6α , where α (e.g., 380 nm) is the lattice constant of the photonic crystals. The band diagram **200** shown in FIG. 2 indicates that the slotted photonic crystals still have a single-mode region when the defect width (W) is enlarged to $1.6W$, where $W = \sqrt{3}\alpha$ is the width of the normal line defect [16]. The thick dashed line **202** is the light line. The gray regions **204** represent the continuum of extended modes. The dotted curve **206** indicates the created defect mode. The inset **208** shows the supercell model defined in PWE simulation.

The guided mode is a quasi-transverse-electric (quasi-TE) mode with slow light effect near the band edge. Based on Maxwell's equations, when the transverse electric field of the quasi-TE mode (E_x) undergoes strong dielectric constant discontinuity of the slot walls, the immediate electric field is much higher at the low-index side [8]. It has been experimentally demonstrated that the field amplitude remains high all across the slot if the slot width is much smaller than the field decay length $1/\gamma_s - 4.0\alpha$, where γ_s is the field decay coefficient in the slot [9]. Based on the same operation principle, the slot width (W_{slot}) of the slot PCW **100** is set to 0.25α and a high E-field confinement is obtained in the slot as shown in FIG. 3, which is a 3D profile of the transverse electric field amplitude of the quasi-TE mode in a slot photonic crystal waveguide **100**, where $\alpha = 380$ nm, $d = 190$ nm, $h = 228$ nm, $W_{slot} = 95$ nm, $W = 1053$ nm, $n_{Si} = 3.48$ and $n_{SiO_2} = 1.46$. Simulation is based on 3D finite-difference time-domain (FDTD) method. The structure features of the slot PCW **100** nicely match the requirements for active material-based silicon devices: the guided mode produces high electric field in a low-index region, creating an opportunity for various low-index electro-optical materials; the slow group velocity of the defect mode can drastically enhance the electro-optical effect and thereby open up the possibility of ultra-compact nonlinear devices. Moreover, as the width of the center slot region is less than 100 nm, the novel photonic crystal structure provides a convenient way to generate sufficient external electric field for active materials with low driving voltage.

The design and optimization of a MMI coupler in accordance with the present invention will now be described. FIGS. 4 and 5 show a mode contour comparison of a slot PCW **100** (FIG. 4) and a single-mode silicon strip waveguide **602** (FIG. 5). As can be seen in the FIGURES, a large coupling loss is inevitable for direct coupling due to the mode-size and mode-shape mismatch. A common solution is to introduce a single-mode to multi-mode waveguide taper structure. However, as previously described, the tapering structure requires a minimal taper length of several hundred of microns to reduce the propagation loss due to mode transformation. As shown in FIG. 6, the MMI coupler **600** in accordance with the present invention is a much more compact mode converter.

Multimode power splitter structures are often used to achieve equi-phase, balanced power partition from one single-mode input waveguide [17]. According to the principle of symmetric modal interference in a multimode waveguide [17]: the input signal excites the fundamental and second-

second-order mode shifted by the phase difference. The phase difference is given by

$$\Delta\sigma = (\beta_0 - \beta_2)L_M,$$

where L_M is the length of the multimode section and β_0 and β_2 are the propagation constants of the fundamental and second-order modes in the multimode waveguide, respectively. The length (L_M) of the multimode section **600** is adjusted to change the phase difference between 0 and π such that the resultant mode profile can best match the slot PCW **100**. The multimode section **600** is designed to support two symmetric modes with $W_M = 1.6W$. The single-mode input waveguide is centered with respect to the multimode section and will therefore excite only the even symmetric modes. With different L_M assumed, the coupling efficiency η is estimated by the overlap integral between the output mode of the multimode section and the guided mode of the slot PCW **100**. FIG. 6 shows the optimization of the mode overlap integral between the slot PCW **100** and the multimode section **602**. The integral is calculated as a function of the length L_M of the multimode section **600** and the phase difference of the excited even modes. FIG. 6 shows that a π phase difference of the even modes in the multimode waveguide provides the best coupling efficiency from the silicon strip waveguide to the slotted PCW **100**, and that coupling efficiencies in excess of 95% can be achieved.

The FDTD method is applied to simulate the evolution of transverse electric field and optical transmission along the propagation direction. The results are shown in FIG. 7 where a group of 3D E_x profiles in X-Y plane are imaged at different Z positions. The transfer region begins at $Z = 0$ μm . The inset **702** shows the transmission of the guided quasi-TE mode as a function of propagation distance. The MMI coupler **600** is located between $Z = 0$ μm and $Z = 1.25$ μm . An efficient mode coupling from the conventional silicon strip waveguide **602** to the novel slot PCW **100** is confirmed. An efficient mode conversion from the conventional silicon strip waveguide to the slot PCW is completed within a 3 μm distance. The FDTD simulation confirms the total insertion loss induced by mode conversion is less than 1 dB. The coupling efficiency for a PCW also depends on the termination of the photonic crystal waveguide. [18] The present invention simulated the coupling structure with different PCW terminations and the best outcome is obtained when the MMI section **600** interfaces with the slot PCW **100** at the edge of the period which gives termination parameter $\tau = 0$, as also indicated in FIG. 1. FIG. 8(a) is a scanning electron microscopy picture with a top view of a slot PCW **100** integrated with two MMI couplers **600** with an insert enlarging the coupling region in accordance with the present invention.

Now referring to FIG. 9, the manufacturing process **900** and measurement results for the slot PCW **100** with MMI coupler **600** will now be described. A silicon-on-insulator (SOI) wafer with a buried oxide layer (e.g., 1- μm) and a top silicon layer (e.g., 250-nm) is provided in block **902**. A hexagonal lattice photonic crystal slab layer **104** is formed in block **904**. The hexagonal lattice photonic crystal slab layer **104** is then patterned to form a plurality of crystal holes and a center trench **102** of a slot photonic crystal waveguide **100** (e.g., lattice constant $\alpha = 360/380$ nm and the hole diameter $d = 0.5\alpha$), and a multimode interference coupler **600** at one or both ends of the center trench **102** using electron-beam lithography followed by reactive ion etching (RIE) and piranha cleaning in block **906**. Different lattice constants are employed to measure the optical transmission spectra for both guided mode and leaky modes of the waveguide **100**. The multimode interference coupler **600** has a coupling efficiency to the slot photonic crystal waveguide **100** greater than or equal to 90%, a width (W_M) that is approximately equal to

a defect width (W) of the slot photonic crystal waveguide **100**, a length (L_M) that is equal to or less than $1.5\ \mu\text{m}$, and interfaces with the slot photonic crystal waveguide **100** at an edge of a period that gives a termination parameter (τ) of approximately zero. The crystal holes and the center trench **102** are filled with a spin-on-glass (SOG) material in block **908**. The silicon-on-insulator wafer is postbaked (e.g., 425°C . for 1 hour) to achieve partial decarbonization in block **910**. The refractive index of SOG after hard baking is $n_{\text{SOG}}=1.42$ that is close to low-index electro-optical materials. At least the multimode interference coupler **600** and the slot photonic crystal waveguide **100** are then coated with an acrylic-based polymer layer that is optically transparent for a specified wavelength (e.g., 1550 nm) in block **912**. Note that the step of patterning the hexagonal lattice photonic crystal slab layer in block **906** can further form an insulation gap **1200** (see FIG. **12**) disposed between the multimode interference coupler **600** and the slot PCW **100**, wherein the length of the multimode interference coupler **600** is reduced by approximately one half of a width of the insulation gap **1200**. FIG. **8(b)** is a picture of a cross-sectional view of the slot PCW **100** before (top) and after (bottom) filling SOG in accordance with the present invention. FIG. **10** confirms that all the void nanostructures in the waveguide slab layer have been filled with SOG. As the last step, an acrylic-based polymer layer that is transparent at $1.55\ \mu\text{m}$ is coated to avoid symmetry-breaking background, where the guided modes can no longer be classified as even or odd and the band gap no longer exists [19].

FIG. **8(c)** shows an enlarged portion of the dispersion diagram for the guided mode (top graph) and a transmission spectra of a $320\ \mu\text{m}$ slot PCW **100** with (solid **802**) and without (dashed **804**) the MMI coupler **600** (bottom graph) in accordance with the present invention. The spectrum is normalized by the transmission through a reference waveguide. The parameters of the slot PCW **100** measured in FIG. **8(c)** are $\alpha=383\text{ nm}$, $d=207\text{ nm}$, $W_{\text{slot}}=97\text{ nm}$, $W_{\text{strip}}=486\text{ nm}$, $W_M=1048\text{ nm}$, $L_M=1260\text{ nm}$, and $h=237\text{ nm}$. To measure the insertion loss induced by mode mismatch, a symmetric 1×2 power splitter was integrated before the slot PCW **100** and introduced a reference arm composed of a strip waveguide to normalize the output of the slot PCW arm. Two samples are fabricated: one sample has MMI couplers **600** at the ends of the slot PCW **100**, the other has the slot PCW **100** directly coupled to the stripe waveguides. The length of the slot PCW **100** in both cases is $320\ \mu\text{m}$. Compared with direct coupling, a 20 dB transmission enhancement over 35 nm optical bandwidth was found when the coupling structure **600** is employed. The insertion loss for the guided mode is less than 5 dB at the peak wavelength of 1557 nm . The measured band edge appears at a normalized frequency of 0.243 ($\lambda=1576\text{ nm}$). The observed spectral range agrees well with the calculated band diagram for the quasi-TE mode of the slot PCW **100**. The slight frequency discrepancy can be attributed to the dimension and index differences between the simulated and fabricated waveguide structures.

The experimental results of the optical spectra for both guided mode and leaky modes are shown in FIG. **11**. The top panels **1102** and **1104** show enlarged portions of the photonic band structure for both guided and leaky modes. The bottom panels **1106** and **1108** show transmission spectrum of the slot PCW **100** of $320\ \mu\text{m}$ length with (solid **1110**) and without (dashed **1112**) coupling structures **600**. The spectrum is normalized on transmission through a reference optical circuit. Compared with direct coupling, one can find a 20 dB efficiency enhancement for the guided mode when the coupling structure is employed. The insertion loss for the guided mode is less than 5 dB. The measured band edge with slow light

effect appears at the normalized frequency of 0.243. Comparing with the calculated band diagram for quasi-TE mode of the slotted photonic crystals, good agreement can be found between the simulated and experimental results. The frequency discrepancy is mainly due to the dimension difference between the simulated and fabricated waveguide structures. The mode mixing effect caused by the weak vertical asymmetry of the final device also induces some resonances in the spectrum [20].

Now referring to FIG. **12**, a MMI coupler **600** between a slot PCW **100** and strip waveguide **602** in accordance with another embodiment of the present invention is shown. The present invention achieves more efficient transmission control from structural innovation and optimization in order to meet the miniaturization demand of high performance micro-/nano-very-large-scale-integration (VLSI) photonic circuit. In this embodiment, an insulation gap or oxide slot **1200** is positioned perpendicular to the slot **102** of the slot PCW **100** at the interface between the slot PCW **100** and the MMI coupler **600**. The insulation gap **1200** can have a width that is approximately equal to a width of a center slot **102** of the slot PCW **100**. Note that the length of the MMI coupler **600** is reduced by approximately one half of a width of the insulation gap **1200**. As before, the interference length L_M and the waveguide width W_M decide the optical mode profile at the interface as well as the coupling efficiency. As will be further described below, the structure shown in FIG. **12** provides an effective index change of as much as 30 times efficiency enhancement compared with the slotted silicon rib waveguide. Such a waveguide layer can serve as the active layer for fully embedded optical interconnect architecture with minimum power consumption.

Silicon has been considered as an attractive material option for low-cost photonic circuits. In contrast to those conventional optoelectronic components fabricated from III-V semiconductor compounds or electro-optic materials such as lithium niobate and nonlinear organic polymers, all-silicon based optical devices offer opportunities for monolithic integration with advanced electronic circuits on a single silicon substrate. In the past few years, high-speed silicon optical modulator [21-23] has been one of the significant advances in pushing device performance for applications ranging from telecommunication down to chip-to-chip interconnection. Nevertheless, it is challenging to achieve efficient optical intensity modulation in silicon because the material does not exhibit any appreciable electro-optic effect [24]. Therefore, a straightforward integration with high-frequency silicon modulator usually requires centimeter-scale active region and inevitable complex electrode design.

The light transmission controller presented here is based on a conventional Mach-Zehnder interferometer with a SOS capacitor embedded in each of the two arms. In order to obtain higher controlling performance, the slot PCW **100** has slow photon effect [22] wherein the width of the defect region (W) is $\sim 1.2\ \mu\text{m}$, the center slot width (W_{slot}) is $\sim 0.1\ \mu\text{m}$, the slab height (h) is $\sim 0.24\ \mu\text{m}$ and the lattice constant (a) of the hexagonal structure is $\sim 0.4\ \mu\text{m}$. Both modeling and experimental data confirm the waveguide operates with a single transmission mode at the wavelength around $1.55\ \mu\text{m}$. Simulation indicates the guided mode is a quasi-transverse-electric mode with greatly reduced group velocity near the band edge.

The design focus of the MMI coupler **600** is to achieve practical output power level at the end of the active waveguide region. The input strip waveguide **602** is centered with respect to the MMI coupler **600** and therefore excites the symmetric modes with tunable phase difference. Parameter optimization indicates the best coupling efficiency is reached when the

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phase difference in the MMI coupler **600** is close to π . Further experimental comparison confirms such coupling structure enhances the coupling efficiency by 20 dB over 35 nm optical bandwidth centered on 1.55 μm . The oxide slot or insulation gap **1200** is introduced in the final device pattern to create strong parallel electric field for carrier accumulation.

A device, such as a symmetric Mach-Zehnder interferometer containing two SOS-capacitor-based phase shifters, with electrodes deposited at both sides of the waveguide region is shown by a microscopic top view in FIG. **13**. To simplify the device fabrication flow and to limit the additional optical absorption from the sandwiched silicon layer, a bulk implantation is implemented on the silicon-on-insulator (SOI) wafer with 1×10^{17} p-doping concentration. Aluminum can be used as the electrode material to achieve acceptable contact resistance. Measurement shows the final resistance after 900° C. thermal annealing is below 5 k Ω .

FIG. **14** shows the simulation and measurement results of the device capacitance as a function of the applied voltage. The noise level of the capacitance measurement **1406** is ~ 6 femtofarad. The capacitance-voltage curve is simulated **1402** and compared with the measurement result **1404**. The deviation of flat-band capacitance is due to positive oxide charges trapped in the center spin-on-glass trench. The curve slope difference is induced by various interface traps around the gate oxide. The negligible asymmetry stems from doping fluctuation and fabrication defects. Based on the measured electrical parameters, calculation shows the resistance-capacitance time constant of the active arm is below 120 ps. Doping profile modification would further reduce the time constant and make the slot waveguide-based silicon structure as a good candidate to realize high-speed transmission control.

Transmission control based on Mach-Zehnder interferometer requires dynamic phase shift between the two waveguide arms. The phase change in slot PCW **100** depends on the mode group velocity, the band shift and the total interaction length. Here carrier accumulation-induced plasma dispersion effect is applied to generate the expected band shift. FIG. **15** shows the measured modulation curve **1502** and the simulation result **1504**. Both of them indicate ~ 6 V driving voltage is required to generate the π -phase shift between two interference arms. The evaluation of band shift distance is based on the plane-wave expansion (PWE) method.

In order to compare the efficiency of transmission control, the effective index change Δn_{eff} of both slot PCW **100** (line **1602** (simulated) and line **1604** (measured)) and slot rib waveguide (line **1606**) are calculated, as shown in FIG. **16**. With different driving voltage applied, the slot PCW **100** always provides as much as 30 times Δn_{eff} -enhancement compared with the slot rib waveguide. The significant enhancement stems from the slow light effect of the photonic crystal waveguide. Power consumption and device size needed to modulate an optical signal are thus significantly reduced. This advantage is crucial for fully embedded board level interconnect **1700** [25-28] as indicated in FIG. **17** where heat dissipation due to the fully embedded structure is a paramount concern. The fully embedded board level optical interconnect **1700** with an indirect modulation employs a photonic crystal waveguide modulator **1702** where a CW laser **1704** is attached to provide constant light source. The spectrum is normalized by the transmission through a reference waveguide. The fully embedded board level optical interconnect **1700** also includes driving electrodes **1706** and vias **1708**. As a result, the present invention provides a carrier accumulation-based efficient transmission controller operating at communication wavelength (1.55 μm). A MMI coupler

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600 is incorporated to implement feasible waveguide combination. The final device is characterized based on electrical and optical performance. The measured device properties indicate that such structural innovation would be a practical option to achieve efficient transmission control based on an all-silicon optical component.

Now referring to FIG. **18A**, a block diagram of a sensor **1800** in accordance with the present invention is shown. The sensor **1800** can be a bio-sensor, chemical sensor, environmental sensor, structural sensor, etc. The sensor **1800** includes a light source **1802**, such as a laser or light emitting device, optically coupled to a strip waveguide **602a**. The strip waveguide **602a** is optically coupled to a multimode interference coupler **600a** which is optically coupled to the slot photonic crystal waveguide **100**. The slot photonic crystal waveguide **100** is optically coupled to a photonic element containing one or more samples **1802** which is optically coupled to a multimode interference coupler **600b**. The multimode interference coupler **600b** is optically coupled to a strip waveguide **602b** which is optically coupled to a detector **1804**. The sensor **1800** may also include various optical switching devices, controllers, converters, bends, splitters, etc. Note that the samples may include one or more analytes, which is a molecule, chemical, compound, particle, cell fragment, cell, or biological entity for which the amount will be quantified. Examples of analytes include proteins, such as hormones or enzymes; glycoproteins; peptides; small molecules; polysaccharides; antibodies; nucleic acids; drugs, including drugs of abuse; toxins; inorganic particles such as colloidal gold particles; viruses or virus particles; bacteria; whole cells; portions of bacteria or cells; heavy metals; salts; isotopes; elements; nanoparticles; metal nanoparticles; semiconductor compositions (CdS or ZnS); dyes; electrolytes; waste; THC; polymers; aromatic compositions; amino acids; hormones; antibodies; receptors; antigens; and other compounds. The analytes can be used to detect what is in the one or more samples, the concentration of the one or more samples, etc.

Referring now to FIG. **18B**, a block diagram of a sensor **1850** in accordance with the present invention is shown. The sensor **1850** can be a bio-sensor, chemical sensor, structural sensor, etc. The sensor **1850** includes a light source **1802**, such as a laser or light emitting device, optically coupled to a strip waveguide **602a**. The strip waveguide **602a** is optically coupled to a multimode interference coupler **600a** which is optically coupled to the slot photonic crystal waveguide **1852**. The slot photonic crystal waveguide **1852** is optically coupled to a multimode interference coupler **600b**. The multimode interference coupler **600b** is optically coupled to a strip waveguide **602b** which is optically coupled to a detector **1804**. At least a portion of the center slot **102** of the slot photonic crystal waveguide **1852** is configured to receive one or more samples. The sensor **1850** may also include various optical switching devices, controllers, converters, bends, splitters, etc. Note that the samples may include one or more analytes, which is a molecule, chemical, compound, particle, cell fragment, cell, or biological entity for which the amount will be quantified. Examples of analytes include proteins, such as hormones or enzymes; glycoproteins; peptides; small molecules; polysaccharides; antibodies; nucleic acids; drugs, including drugs of abuse; toxins; inorganic particles such as colloidal gold particles; viruses or virus particles; bacteria; whole cells; portions of bacteria or cells; heavy metals; salts; isotopes; elements; nanoparticles; metal nanoparticles; semiconductor compositions (CdS or ZnS); dyes; electrolytes; waste; THC; polymers; aromatic compositions; amino acids; hormones; antibodies; receptors; antigens; and other com-

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pounds. The analytes can be used to detect what is in the one or more samples, the concentration of the one or more samples, etc. Note that the combination of the insertion of the analytes into the slot region, enhanced sensitivity by slow light effect and concentration of photon energy in the slot region can increase sensitivity of the sensor by two to three orders of magnitude.

Now referring to FIG. 19, the manufacturing process 1900 for a slot PCW 100 having one or more sample recesses within the center slot optically coupled to a MMI coupler 600 that is used as part of a sensor in accordance with the present invention will now be described. A silicon-on-insulator (SOI) wafer with a buried oxide layer (e.g., 1- μm) and a top silicon layer (e.g., 250-nm) is provided in block 902. A hexagonal lattice photonic crystal slab layer 104 is formed in block 904. The hexagonal lattice photonic crystal slab layer 104 is then patterned to form a plurality of crystal holes and a center trench 102 of a slot photonic crystal waveguide 100 (e.g., lattice constant $\alpha=360/380$ nm and the hole diameter $d=0.5\alpha$), wherein at least a portion of the center trench 102 is configured to receive one or more samples, and a multimode interference coupler 600 at one or both ends of the center trench 102 using electron-beam lithography followed by reactive ion etching (RIE) and piranha cleaning in block 1902. Different lattice constants are employed to measure the optical transmission spectra for both guided mode and leaky modes of the waveguide 100. The multimode interference coupler 600 has a coupling efficiency to the slot photonic crystal waveguide 100 greater than or equal to 90%, a width (W_M) that is approximately equal to a defect width (W) of the slot photonic crystal waveguide 100, a length (L_M) that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide 100 at an edge of a period that gives a termination parameter (τ) of approximately zero. The crystal holes are filled with a spin-on-glass (SOG) material in block 1904. Note that the portion of the center trench 102 that is not configured to receive the one or more samples can also be filled with the spin-on-glass (SOG) material in block 1904. The silicon-on-insulator wafer is postbaked (e.g., 425° C. for 1 hour) to achieve partial decarbonization in block 910. The refractive index of SOG after hard baking is $n_{\text{SOG}}=1.42$ that is close to low-index electro-optical materials. At least the multimode interference coupler 600 and the slot photonic crystal waveguide 100, except for the portion of the center trench 102 that is configured to receive the one or more samples, are then coated with an acrylic-based polymer layer that is optically transparent for a specified wavelength (e.g., 1550 nm) in block 1906. Note that the step of patterning the hexagonal lattice photonic crystal slab layer in block 906 can further form an insulation gap 1200 (see FIG. 12) disposed between the multimode interference coupler 600 and the slot PCW 100, wherein the length of the multimode interference coupler 600 is reduced by approximately one half of a width of the insulation gap 1200. Note that the samples may include one or more analytes, which is a molecule, chemical, compound, particle, cell fragment, cell, or biological entity for which the amount will be quantified. Examples of analytes include proteins, such as hormones or enzymes; glycoproteins; peptides; small molecules; polysaccharides; antibodies; nucleic acids; drugs, including drugs of abuse; toxins; inorganic particles such as colloidal gold particles; viruses or virus particles; bacteria; whole cells; portions of bacteria or cells; heavy metals; salts; isotopes; elements; nanoparticles; metal nanoparticles; semiconductor compositions (CdS or ZnS); dyes; electrolytes; waste; THC; polymers; aromatic compositions; amino acids; hormones; antibodies; receptors; antigens; and other compounds.

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It will be understood that particular embodiments described herein are shown by way of illustration and not as limitations of the invention. The principal features of this invention can be employed in various embodiments without departing from the scope of the invention. Those skilled in the art will recognize, or be able to ascertain using no more than routine experimentation, numerous equivalents to the specific procedures described herein. Such equivalents are considered to be within the scope of this invention and are covered by the claims.

All publications and patent applications mentioned in the specification are indicative of the level of skill of those skilled in the art to which this invention pertains. All publications and patent applications are herein incorporated by reference to the same extent as if each individual publication or patent application was specifically and individually indicated to be incorporated by reference.

The use of the word “a” or “an” when used in conjunction with the term “comprising” in the claims and/or the specification may mean “one,” but it is also consistent with the meaning of “one or more,” “at least one,” and “one or more than one.” The use of the term “or” in the claims is used to mean “and/or” unless explicitly indicated to refer to alternatives only or the alternatives are mutually exclusive, although the disclosure supports a definition that refers to only alternatives and “and/or.” Throughout this application, the term “about” is used to indicate that a value includes the inherent variation of error for the device, the method being employed to determine the value, or the variation that exists among the study subjects.

As used in this specification and claim(s), the words “comprising” (and any form of comprising, such as “comprise” and “comprises”), “having” (and any form of having, such as “have” and “has”), “including” (and any form of including, such as “includes” and “include”) or “containing” (and any form of containing, such as “contains” and “contain”) are inclusive or open-ended and do not exclude additional, unrecited elements or method steps.

The term “or combinations thereof” as used herein refers to all permutations and combinations of the listed items preceding the term. For example, “A, B, C, or combinations thereof” is intended to include at least one of: A, B, C, AB, AC, BC, or ABC, and if order is important in a particular context, also BA, CA, CB, CBA, BCA, ACB, BAC, or CAB. Continuing with this example, expressly included are combinations that contain repeats of one or more item or term, such as BB, AAA, MB, BBC, AAABCCCC, CBBAAA, CABABB, and so forth. The skilled artisan will understand that typically there is no limit on the number of items or terms in any combination, unless otherwise apparent from the context.

All of the compositions and/or methods disclosed and claimed herein can be made and executed without undue experimentation in light of the present disclosure. While the compositions and methods of this invention have been described in terms of preferred embodiments, it will be apparent to those of skill in the art that variations may be applied to the compositions and/or methods and in the steps or in the sequence of steps of the method described herein without departing from the concept, spirit and scope of the invention. All such similar substitutes and modifications apparent to those skilled in the art are deemed to be within the spirit, scope and concept of the invention as defined by the appended claims.

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- What is claimed is:
 1. An optical apparatus comprising a multimode interference coupler configured to optically couple a strip waveguide to a slot photonic crystal waveguide wherein the multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μ m, and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.
 2. The optical apparatus as recited in claim 1, wherein the length of the multimode interference coupler is equal to or less than 1.26 μ m.
 3. The optical apparatus as recited in claim 1, wherein the coupling efficiency is greater than or equal to 95%.
 4. The optical apparatus as recited in claim 1, wherein: the width of the multimode interference coupler is approximately equal to $1.6\sqrt{3}\alpha$ where α is a lattice constant of the slot photonic crystal waveguide; and the length of the multimode interference coupler is approximately equal to $\pi/(\beta_0 - \beta_2)$ where β_0 is a fundamental mode propagation constant in the multimode interference coupler and β_2 is a second order propagation constant in the multimode interference coupler.
 5. The optical apparatus as recited in claim 1, further comprising an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide.
 6. The optical apparatus as recited in claim 5, wherein the multimode interference coupler provides an efficiency enhancement of approximately thirty times that of a slotted silicon rib waveguide.
 7. The optical apparatus as recited in claim 5, wherein a width of the insulation gap is approximately equal to a width of a center slot of the slot photonic crystal waveguide.
 8. The optical apparatus as recited in claim 5, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.
 9. The optical apparatus as recited in claim 1, wherein the optical apparatus is integrated into a sensor, a router, or a fully embedded board level interconnect.
 10. The optical apparatus as recited in claim 1, wherein the optical apparatus is integrated into a sensor wherein: one or more samples are deposited within at least a portion of a center slot of the slot photonic crystal waveguide; or the samples are deposited within one or more recesses aligned with a center slot of the slot photonic crystal waveguide.
 11. The optical apparatus as recited in claim 10, wherein the one or more samples comprise one or more analytes.
 12. An optical apparatus comprising a multimode interference coupler configured to optically couple a strip waveguide to a slot photonic crystal waveguide wherein the multimode

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interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to $1.6\sqrt{3}\alpha$ where α is a lattice constant of the slot photonic crystal waveguide, a length that is approximately equal to $\pi/(\beta_0 - \beta_2)$ where β_0 is a fundamental mode propagation constant in the multimode interference coupler and β_2 is a second order propagation constant in the multimode interference coupler, and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.

13. The optical apparatus as recited in claim 12, further comprising an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

14. The optical apparatus as recited in claim 12, wherein the multimode interference coupler provides an efficiency enhancement of approximately thirty times that of a slotted silicon rib waveguide.

15. The optical apparatus as recited in claim 12, wherein a width of the insulation gap is approximately equal to a width of a center slot of the slot photonic crystal waveguide.

16. An optical apparatus comprising:

a strip waveguide;

a slot photonic crystal waveguide; and

a multimode interference coupler disposed between the strip waveguide and the slot photonic crystal waveguide, wherein the multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.

17. The optical apparatus as recited in claim 16, further comprising an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

18. The optical apparatus as recited in claim 16, wherein the multimode interference coupler provides an efficiency enhancement of approximately thirty times that of a slotted silicon rib waveguide.

19. The optical apparatus as recited in claim 16, wherein the optical apparatus is integrated into a sensor wherein:

one or more samples are deposited within at least a portion of a center slot of the slot photonic crystal waveguide; or the samples are deposited within one or more recesses aligned with a center slot of the slot photonic crystal waveguide.

20. The optical apparatus as recited in claim 19, wherein the one or more samples comprise one or more analytes.

21. A method for improving performance of an optical communication system comprising the steps of:

designing a multimode interference coupler having a width that is approximately equal to $1.6\sqrt{3}\alpha$ where α is a lattice constant of a slot photonic crystal waveguide, a length that is approximately equal to $\pi/(\beta_0 - \beta_2)$ where β_0 is a fundamental mode propagation constant in the multimode interference coupler and β_2 is a second order propagation constant in the multimode interference coupler; and

fabricating the multimode interference coupler between a strip waveguide and the slot photonic crystal waveguide

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such that the multimode interference coupler interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero.

22. The method as recited in claim 21, further comprising the step of fabricating an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

23. A method for manufacturing an optical apparatus comprising the steps of:

providing a silicon-on-insulator wafer with a buried oxide layer and a top silicon layer;

forming a hexagonal lattice photonic crystal slab layer;

patterning the hexagonal lattice photonic crystal slab layer to form a plurality of crystal holes and a center trench of a slot photonic crystal waveguide, and a multimode interference coupler at one or both ends of the center trench using electron-beam lithography followed by reactive ion etching and piranha cleaning, wherein the multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero;

filling the crystal holes and the center trench with a spin-on-glass material;

postbaking the silicon-on-insulator wafer to achieve partial decarbonization; and

coating at least the multimode interference coupler and the slot photonic crystal waveguide with an acrylic-based polymer layer that is optically transparent for a specified wavelength.

24. The method as recited in claim 23, wherein the step of patterning the hexagonal lattice photonic crystal slab layer further forms an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

25. A method for manufacturing an optical apparatus comprising the steps of:

providing a silicon-on-insulator wafer with a buried oxide layer and a top silicon layer;

forming a hexagonal lattice photonic crystal slab layer;

patterning the hexagonal lattice photonic crystal slab layer to form a plurality of crystal holes and a center trench of a slot photonic crystal waveguide, and a multimode interference coupler at one or both ends of the center trench using electron-beam lithography followed by reactive ion etching and piranha cleaning, wherein the multimode interference coupler has a coupling efficiency to the slot photonic crystal waveguide greater than or equal to 90%, a width that is approximately equal to a defect width of the slot photonic crystal waveguide, a length that is equal to or less than 1.5 μm , and interfaces with the slot photonic crystal waveguide at an edge of a period that gives a termination parameter of approximately zero, and wherein at least a portion of the center trench is configured to receive one or more samples;

filling the crystal holes with a spin-on-glass material;

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postbaking the silicon-on-insulator wafer to achieve partial decarbonization; and
coating at least the multimode interference coupler and the slot photonic crystal waveguide, except for the portion of the center trench that is configured to receive the one or more samples, with an acrylic-based polymer layer that is optically transparent for a specified wavelength.
26. The method as recited in claim 25, wherein the step of patterning the hexagonal lattice photonic crystal slab layer

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further forms an insulation gap disposed between the multimode interference coupler and the slot photonic crystal waveguide, wherein the length of the multimode interference coupler is reduced by approximately one half of a width of the insulation gap.

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